

PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.116
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 1792**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Shigehiro NISHINO et al.

Group Art Unit: 1792

Application No.: 10/520,141

Examiner: M. SONG

Filed: September 1, 2005

Docket No.: 122261

For: LARGE-DIAMETER SIC WAFER AND MANUFACTURING METHOD THEREOF

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR §1.116

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the November 26, 2007 Office Action, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.